

Warm Isostatic Press For Solid State Battery Research

Item Number: PCIH



Introduction

Discover the advanced Warm Isostatic Press (WIP) for semiconductor lamination. Ideal for MLCC, hybrid chips, and medical electronics. Enhance strength and stability with precision.

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Instrument model	PCIH-20T	PCIH-40T	PCIH-60T	PCIH-100T
Pressure Range	0-20T	0-40T	0-60.0 tons	0-100 tons
Piston diameter	130mm (d) in chrome plated oil cylinder	150mm (d) in chrome plated oil cylinder	200mm (d) in chrome plated oil cylinder	220mm (d) in chrome plated oil cylinder
Pressurization process	Program pressurization - Program holding-Timed pressure relief			
Hold time	1 second to 999 minutes	1 second to 999 minutes	1 second to 999 minutes	1 second to 999 minutes
Pressure conversion	The program automatically converts the pressure borne by the sample			
Display	7 inch LCD screen	7 inch LCD screen	7 inch LCD screen	7 inch LCD screen
Heating temperature	Room temperature-200.0C	Room temperature-200.0C	Room temperature-200.0C	Room temperature-200.0C
Isostatic pressure	300MPa	300MPa	300MPa	500MPa
Isostatic chamber size	Φ30×150mm(M×N)	Φ40×150mm(M×N)	Φ×50×150 (M×N)	Φ×50×150 (M×N)
Piston stroke (T)	50mm	50mm	50mm	50mm